

	Type	Hits	Search Text	DBs	Time Stamp	Comments	Error Defin	Errors	Ref #
1	BRS	207	semiconductor and characteristic and fabricate and substrate and classify\$3	US-PGPUB; USPAT	2005/05/31 08:24				S1
2	BRS	692	mahalanobis	US-PGPUB; USPAT	2005/05/31 08:24				S2
3	BRS	0	S1 and S2	US-PGPUB; USPAT	2005/05/31 08:24				S3
4	BRS	113	S2 and semiconductor	US-PGPUB; USPAT	2005/05/31 08:24				S4
5	BRS	61	S4 and classify\$3	US-PGPUB; USPAT	2005/05/31 08:25				S5
6	BRS	53	S5 and test	US-PGPUB; USPAT	2005/05/31 08:25				S6
7	BRS	50	S6 and distance and compar\$3	US-PGPUB; USPAT	2005/05/31 08:25				S7
8	BRS	47	S7 and space	US-PGPUB; USPAT	2005/05/31 08:25				S8
9	BRS	6	S8 and fabricate\$3	US-PGPUB; USPAT	2005/05/31 08:28				S9
10	BRS	5310	semiconductor and classify\$3	US-PGPUB; USPAT	2005/05/31 08:28				S10
11	BRS	32	S10 and test near1 element and substrate	US-PGPUB; USPAT	2005/05/31 08:32				S11
12	BRS	1	S11 and mahalanobis	US-PGPUB; USPAT	2005/05/31 08:51				S12
13	BRS	0	mahalanobis and classify\$3 near1 semiconductor	US-PGPUB; USPAT	2005/05/31 08:52				S13
14	BRS	113	mahalanobis and semiconductor	US-PGPUB; USPAT	2005/05/31 08:52				S14
15	BRS	749103	14a dn fabricat\$3	US-PGPUB; USPAT	2005/05/31 08:53				S15
16	BRS	18	S14 and fabricat\$3	US-PGPUB; USPAT	2005/06/08 19:09				S16

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	U	Document ID	Issue Date	Pages	Title	Current OR	Current XRe	Retrieval	Inventor	S	C	P	2	3
1		US 20050074834 A1	20050407	144	Method and system for classifying a scenario	435/34	702/19		Chaplen, Frank W.R. et al.					
2		US 20050028932 A1	20050210	40	Method and apparatus for real-time dynamic chemical analysis	156/345.15			Shekel, Yehuda et al.					
3		US 20040228186 A1	20041118	19	Analysis method for semiconductor device, analysis system and a computer program product	365/202			Kadota, Kenichi					
4		US 20040219590 A1	20041104	56	Methods of detecting targets on an array	435/6	435/287.2		Dickinson, Todd et al.					
5		US 20030059104 A1	20030327	18	Pattern evaluation system, pattern evaluation method and program	382/145	382/192		Mitsui, Tadashi					
6		US 20020193891 A1	20021219	28	Apparatus for diagnosing failure in equipment using signals relating to the equipment	700/21	700/17; 700/79; 700/80; 700/83		Ishiku, Yukihiro					
7		US 20020156549 A1	20021024	22	Controlling method for manufacturing process	700/108	700/111; 700/116; 700/262		Hayashi, Shunji					
8		US 20020154315 A1	20021024	43	Optical computational system	356/305	359/326		Myrick, Michael L.					
9		US 20020102578 A1	20020801	56	Alternative substrates and formats for bead-based array of arrays TM	435/6	435/287.2		Dickinson, Todd et al.					
10		US 20010020284 A1	20010906	43	Method and device for analyzing data	714/37			Tsuda, Hidetaka et al.					
11		US 6862484 B2	20050301	22	Controlling method for manufacturing process	700/73	700/110; 700/121; 700/125		Hayashi, Shunji					

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments	Error	Definit	Er
1	IS&R	L1	2	((("5274434") or ("5726920")).PN.	US-PG PUB; USPAT	2005/06/0 8 16:25				
2	IS&R	L4	1	("6438440").PN.	US-PG PUB; USPAT	2005/06/0 8 19:09				

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